


 FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE
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 INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

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 ATTY. DOCKET NO.
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 SERIAL NO.
10/622,843

 APPLICANT
Wiesmann, et al.

 CONFIRMATION NO.
4758

 FILING DATE
July 18, 2003

 GROUP
1763

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
BT	5,231,074	July 27, 1993	Cima et al.			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

BT		1. Author: Chan et al.; Title: "Effect of the Post-Deposition Processing Ambient on the Preparation of Superconducting $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ Coevaporated Thin Films Using a BaF_2 Source;" Publication: <i>Appl. Phys. Lett.</i> 53(15): 1443-1445; Date of Publication: October 1988.
		2. Author: Solovyov et al.; Title: "Ex-situ Post-deposition Processing for Large Area $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films and Coated Tapes;" Publication: <i>IEEE Transactions on Applied Superconductivity</i> 11(1):2939-2942; Date of Publication: March 2001.
		3. Author: Solovyov et al.; Title: "Thick $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films by Post Annealing of the Precursor by High Rate E-beam Deposition on SrTiO_3 Substrates;" <i>Physica C</i> 309: 269-274; Date of Publication: December 1998.
		4. Author: Solovyov et al.; Title: "High Rate Deposition of 5 Micron Thick $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films using the BaF_2 Ex-Situ Post Annealing Process;" Publication: <i>IEEE Transactions on Applied Superconductivity</i> 9(2):1467-1470; Date of Publication: June 1999.
		5. Author: Solovyov et al.; Title: "Growth rate limiting mechanisms of $\text{YBa}_2\text{Cu}_3\text{O}_7$ films manufactured by ex situ processing;" Publication: <i>Physica C</i> 353:14-22; Date of Publication: 2001.
BT		6. U.S. Application Publication No. 2003/0050195. 03/13/2003 Wiesmann et al.

EXAMINER

BTa BT

DATE CONSIDERED

9/12/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication with applicant.